

3. (Original) An evaluation method for polycrystalline silicon as set forth in claim 1, wherein the polycrystalline silicon immersed in the agent is aggregated or in pellet shape.

4. (Original) An evaluation method for polycrystalline silicon as set forth in claim 2, wherein the polycrystalline silicon immersed in the agent is aggregated or in pellet shape.

5. (Currently amended) An evaluation method for polycrystalline silicon as set forth in claim 1, further comprising a the step of:

analyzing the composition of the foreign particles.

6. (Currently amended) An evaluation method for polycrystalline silicon as set forth in claim 2, further comprising a the step of:

analyzing the composition of the foreign particles.

7. (Currently amended) An evaluation method for polycrystalline silicon as set forth in claim 3, ~~further comprising a step of: 1,~~  
~~analyzing the composition of the~~ wherein said foreign particles cause crystal defects.

8. (Currently amended) An evaluation method for polycrystalline silicon as set forth in claim 5, wherein ~~4, further comprising a step of:~~

~~analyzing the composition of the foreign particles~~ the analysis is carried out using scanning electron microscopy of energy dispersive X-ray spectroscopy.

9. (Currently amended) An evaluation method for polycrystalline silicon as set forth in claim 1, further comprising a the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

10. (Currently amended) An evaluation method for polycrystalline silicon as set forth in claim 2, further comprising a the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

11. (Currently amended) An evaluation method for polycrystalline silicon as set forth in claim 3, further comprising a the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

12. (Currently amended) An evaluation method for polycrystalline silicon as set forth in claim 4, further comprising a the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

13. (Currently amended) An evaluation method for polycrystalline silicon as set forth in claim 5, further comprising a the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

14. (Currently amended) An evaluation method for polycrystalline silicon as set forth in claim 6, further comprising a the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

15. (Currently amended) An evaluation method for polycrystalline silicon as set forth in claim 7, further comprising a the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

16. (Currently amended) An evaluation method for polycrystalline silicon as set forth in claim 8, further comprising a the step of:

subjecting the agent to a circulation filtering process prior to the immersion of the polycrystalline silicon in the agent.

17. (New) An evaluation method for polycrystalline silicon as set forth in claim 1, wherein counting the number of foreign particles includes using a measuring device.

18. (New) An evaluation method for polycrystalline silicon as set forth in claim 17, wherein the measuring device is a particle counter.

19. (New) An evaluation method for polycrystalline silicon as set forth in claim 1, wherein the agent is hydrofluoric acid and nitric acid.

